An Integrated Economic <u>and</u> ESH Framework for Making Technology Choices

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NSF/SRC Engineering Research Center

Environmentally Benign Semiconductor Manufacturing Tele-seminar 24th July 2003



ESH – Environment, Safety and Health

COO – Cost of Ownership

They must be seamlessly integrated for effective decision making

Why are Technology Choices Complex?

Example: Choosing a chamber cleaning gas (NF₃ vs. F_2 ?)

Decision Criteria	NF ₃	F ₂	Reference
Fluorine usage rate at the same etch rate (mole/min)	0.15	0.17	This work
Cost/mole of Fluorine	\$6	\$0.8	[1]
LCA Global Warming Effect (kg CO ₂ equivalent/kg)	3.3	2.4	This work
Toxicity LC ₅₀ (ppm)	6700	180	[2,3]

 The Problem:
 How to choose between technologies

 - When there are conflicting decision criteria

 - Many uncertainties

- How much information do we need to know in order to get the sign right?
- How do we decide where to allocate resources for more analyses, experiments and/or better data?



Industry recognition of need

"...There is a critical need for an integrated way to evaluate and qualify environmental impact of process, chemicals, and process equipment..." -- ITRS, 2001 Edition, Environmental, Safety, and Health

Emerging Driving forces for Change

"...The European Commission Integrated Product Policy (IPP) will look at <u>all</u> stages of a product's life cycle from cradle to grave...we are calling on industry to bring IPP to life"

-- M. Wallström, EU Environment Commissioner

Press release 18th June 2003

Outline of Presentation

- Review of Current Approaches
 - CARRI, EnV-S, TEAM,...

Development of Decision criteria

- System boundary choice
- Cost of Ownership (COO)
- Environment, Health and Safety (EHS)
- Integration of COO and EHS
- Impact Assessment Models
 - Process models for mass and energy balances
 - Hierarchical representations
 - Treatment of uncertainties
- Example
 - NF_3 vs. F_2 case study
- Conclusions and Next Steps



Comparison of Environmental Valuation Methods

	CARRI	S70	ТЕАМ	EnV-S
Impact Categories Considered	Work space safety and health, broad characterization of environmental toxicity, regulatory, COO	Mass and energy consumed, transformed, and discharged	More than 50 categories such as global warming effect, human toxicity, aquatic/terrestrial eco- toxicity	COO, human health (cancer, acute toxicity, etc), regulatory
Applications	Relative risk of chemical usage	Determine the overall material and energy usage and waste products generated by the unit operations	naterial and energy sage and wasteenvironmental impacts of the operations associated with products,	
System Boundary	Fab, downstream	Fab	Upstream, fab, downstream	Upstream, fab, downstream
Inputs based on database or model	Database	Static, averaged process model	Based on user input, databases	Process models
Site Specific	Yes	Yes	No	Yes
Linked to Cost	Yes	No	No	Yes
Include Uncertainty	Qualitative	No	User can set up limited probability distributions	PDFs, Monte Carlo simulations
Database availability	Inventories and impacts	Inventories	Inventories and impacts	Inventories

Key points from review of ESH models

- Widespread industry acceptance of SEMI COO model but it is not <u>integrated</u> into ESH methods
- Decision criteria are influenced by the choice of system boundaries but few methods look <u>outside</u> the plant boundaries
- No <u>formalized</u> treatment of uncertainties or means for identifying what controls decision outcomes
- Little consistency between databases used for analyses and there are many data gaps
- Little cross fertilization of good ideas from other industries

A new framework must:

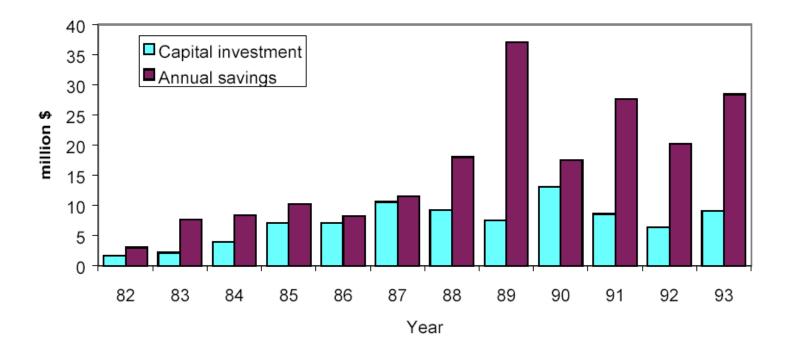
- Be compatible with the short innovation cycle
- Show the value of treating environment as an objective in design and operations
- Handle different levels of understanding in the process and economic models
- Deal with the large EHS information uncertainties

~1 orders of magnitude in air pollutant emission factors

- $2 \sim 3$ orders of magnitude in cancer toxicity indicators
- $3 \sim 6$ orders of magnitude in non-cancer toxicity indicators

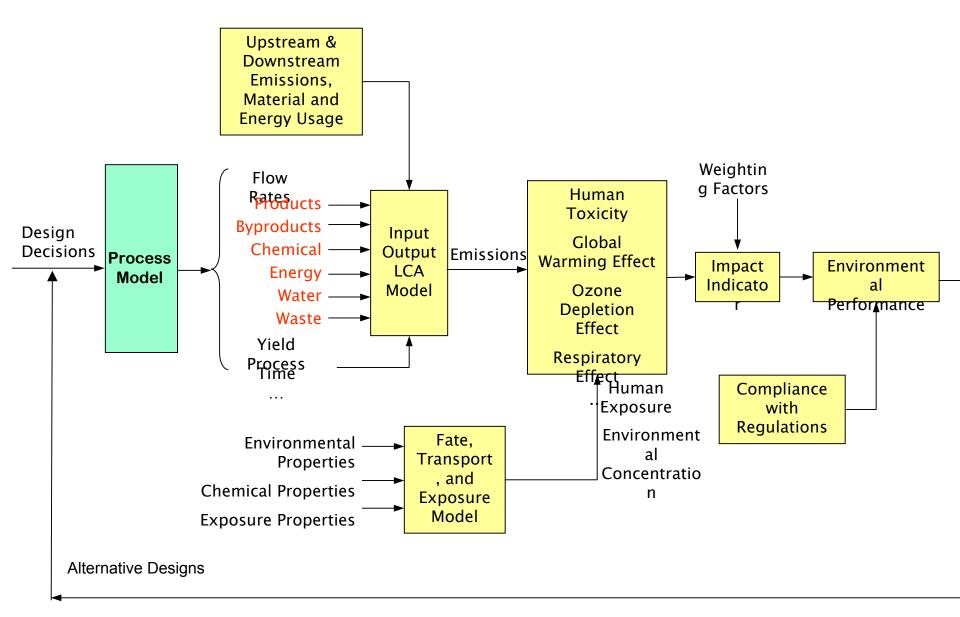
Value of Treating the Environment as an Objective

• The Energy and Waste Reduction Contests at Dow Chemical



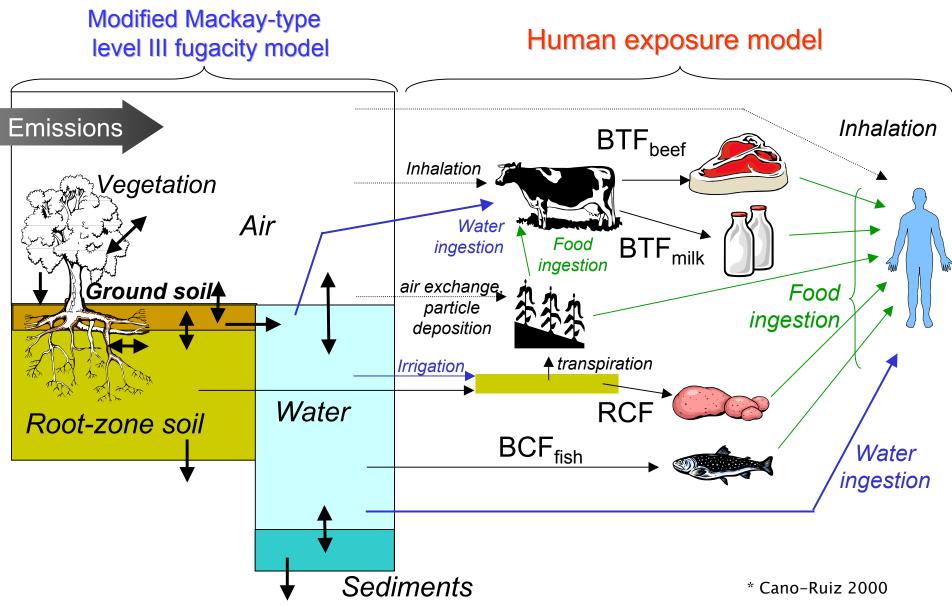
 A 180% annual return on \$3 million invested in projects to reduce toxic waste generation and emissions (Midland site, Dow Chemical).

An Environmental Evaluation Model



Human Exposure Modeling: Complex Interactions*

Very complicated system, large number of parameters





- Model Input Six: Price vector (p)
- Allocation matrix (G): for multiple product processes

$$G_{ji} = \begin{cases} \frac{p_i}{\sum_{k} C_{kj} p_k} & \forall C_{ij} \neq 0\\ 0 & \forall C_{ij} = 0 \end{cases}$$

G_{ji}: the amount of throughput of process j that is attributed to one unit of product i made in process j

• Throughput matrix (D)

 $\mathsf{D}_{ji} = \mathsf{F}_{ji}\mathsf{G}_{ji}$

D_{ji}: the amount of throughput of process j that is attributed to the demand of one unit of product I at current price and market share

Direct product requirement (q_{direct})

$$q_{direct} = (I + BD)d$$

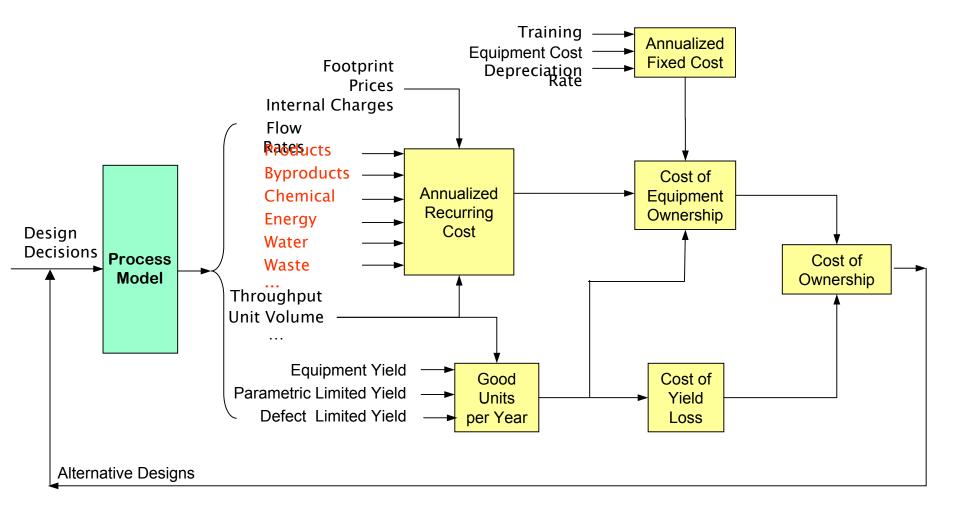
Total product requirements

 $q = (I + A_{prod} + A_{prod}A_{prod} + A_{prod}A_{prod}A_{prod} + \dots)d = (I - A_{prod})^{-1}d$ where $A_{prod} \equiv BD$

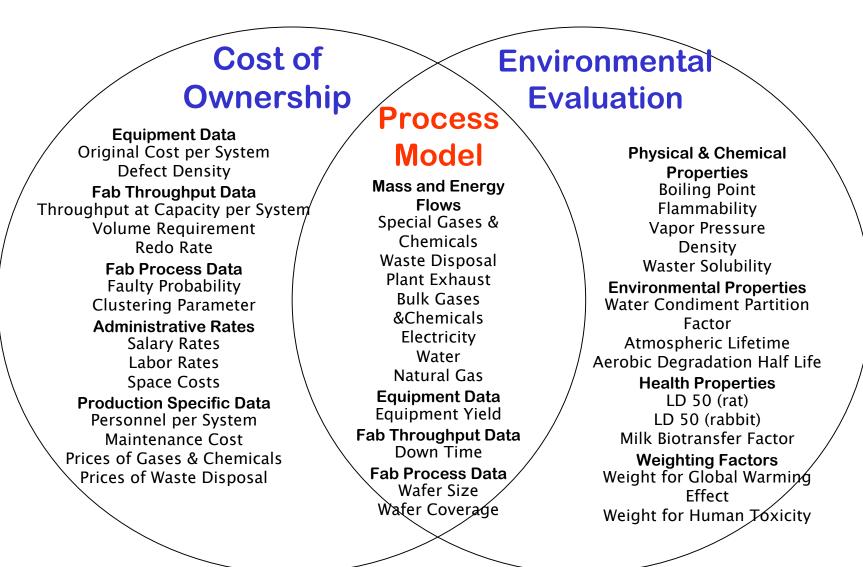


- Total process throughput requirements (x)
 x = Dq
- Life cycle environmental exchanges inventory (e)
 e = Ex
- Impact valuation by process (Ω_{process}) $\Omega_{\text{process}} = \text{Diag}(x) E^T H w$
- Impact valuation by emission ($\Omega_{emission}$) $\Omega_{emission}$ = Diag(e) H w

Cost of Ownership (CoO) Model



Overlapping Data Requirements



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There are many areas of overlap

Matrix Presentation of Cost-of-Ownership

- COO = Cost of Equipment Ownership (CEO) + Cost of Yield Loss (CYL)
- CEO = Fixed Cost + Recurring Cost

• Recurring Cost =
$$\begin{bmatrix} P_{NF_3} & P_{N_2} & P_{Ar} & P_{Energy} & P_{Water} & P_{WasteDisposal} & P_{Lbm} & \dots & P_{Sp} & P_{Sc} \end{bmatrix}$$

 $\times \begin{bmatrix} U_{NF_3} & U_{N_2} & U_{Ar} & U_{Energy} & U_{Water} & U_{WasteDisposal} & U_{Lbm} & \dots & U_{Sp} & U_{Sc} \end{bmatrix}^{-1}$

•
$$CYL = \begin{pmatrix} annualized cost & annualized attributed \\ of wafers lost due & + cost of wafers lost due to \\ to equipment yield & defect & parametric yield \end{pmatrix} \cdot \frac{1}{good units per year}$$

	S PROCESS	Coal furnace	Coal production	Coal-fired power plan	F2 chamber cleaning-	EF2 production	b Industrial gas furnace	• IP Natural gas productio	xi NF3 chamber cleanin	NF3 production	Oil furnace	Oil production	Oil-fired power plant	:	
	kg	0	0	0	0.03	0	0	0	0.03	0	0	0	0		
		0	0	0	0.00	0	0	0	0.00	0	0	0	0		
	kg	1	0	0	0	0	0	0	0	0	0	0	0		
	kg	0	0	0	0	0	0	0	0	0	0	0	0		
	MJ	0	0.05	0	6.55	8	0	0.1	6.55	18	0	0	0		
	kg	0	0	0	0.06	0	0	0	0	3.3	0	0	0		
	kg	0	0	0	0	0	0	0	0	0	0	0	0		
	kg	0	0	0	0	2.5	0	0	0	0	0	0	0		
	kg	0	0	0	0	0.1	0	0	0	0	0	0	0		
	kg	0	0	0	0.05	0.1	0	0	0.05	0	0	0	0		
	kg	0	0	0	0	0	20	0	0	0	0	0	0		
	kg	0	0	0	0	0	0	0	0.07	0	0	0	0		
	kg	0	0	0	0	0	0	0	0	0	23	0	0		
	kg	0	0	0	0	0	0	0	0	0	0	0	0		
	MJ	0	0.01	10	0	0	0	0	0	0	0	0	0		
urnace	MJ	0	0	0	0	0	0	1.3	0	0	0	1	0		
	MJ	0	0	0	0	0	0	0	0	0	0	0	10		
ice	MJ	0	0	0	0	0	0	0	0	0	0	0	0		

PRODUCT INPUTS

Ar
clean chamber
Coal
Diesel fuel
Electricity
F2
Fluorine from Chamber Cleaning
HF
KF
N2
Natural gas
NF3
Oil
SiF4
Thermal energy from coal furnace
Thermal energy from industrial gas furnace
Thermal energy from oil furnace
Thermal energy from utility gas furnace



Time

and cost

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	Pro	Assumption	Likely distributions for gas usage
1	Tolerable efficiency	Yield of = ζ (ζ is a very small number)	100% - efficiency ζefficiency
I	Stoichiometric	100% efficiency, extremely quick etching	
2	Simple kinetics	Only a few key reactions	
3	Detailed kinetics	First principles	
4	Experiments		

18



		Process Model		Likely of for gas	distributions usage
Time nd cost ncrease				1	00% fficiency ζ efficiency
	2	Simple kinetics	Only a few key reactions		
	3	Detailed kinetics	First principles		
	4	Experiments			

Process Modeling Hierarchy and Resource Needs

	Process Model Hierarchy	Distribution of Flows	Resources Needed
1	Simple stoichiometric yield		1
2	Lumped kinetics (3 reactions)		10
3	Detailed kinetics (60 reactions)		100
4	Model based experiments		1000

Simple Stoichiometic Yield Model

Gas	Model	- -	/ mole SiO ₂ η = 100%
NF ₃	$\frac{1}{\eta} \cdot \frac{4SiF_4 + HF}{3}$	1900	95
F_2	$\frac{1}{\eta} \cdot \frac{4SiF_4 + HF}{2}$	1520	76

Lumped Kinetics and CSTR Model

Key Assumptions

- Free electrons are generated mainly by ionization X_2 +e --> X_2 ++2e
- Electron loss and production are linear to electron concentration
- Diffusion of electrons dominates the transport of electrons.

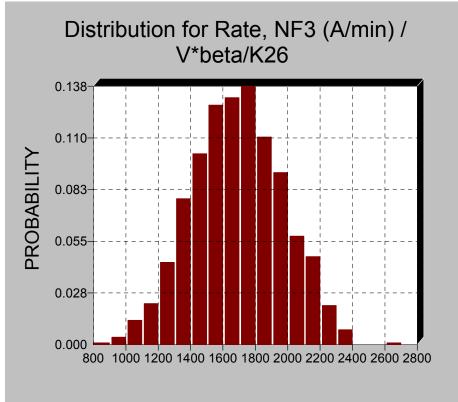
$$\begin{split} NF_{3} + e & -- > NF_{2} + F \cdot + e \\ NF_{2} + e & -- > NF + F \cdot + e \\ NF + e & -- > N + F \cdot + e \\ F_{2} + e & -- > F^{-} + F \cdot \end{split} \\ k_{2} = 1.57E^{-17} T_{e}^{1.8} exp(-27565/T_{e}) \\ k_{1} = 1.57E^{-17} T_{e}^{1.8} exp(-27565/T_{e}) \\ k = 1.02E^{-5} T_{e}^{-0.9} exp(1081.8/T_{e}) \end{split} \\ F \cdot + SiO_{2} - - > SiF_{4} \\ \end{split} \\ r = (8.97 \pm 0.82) \times 10^{-13} n_{F} T_{s}^{1/2} \exp\left(-\frac{0.163 \, eV}{kT_{s}}\right) \end{split}$$

$$n_{F,NF_{3}} = \frac{\beta_{3}\tau n_{NF_{3},in}}{1+\beta_{3}\tau} + \frac{\beta_{2}\beta_{3}\tau^{2}n_{NF_{3},in}}{(1+\beta_{2}\tau)(1+\beta_{3}\tau)} + \frac{\beta_{1}\beta_{2}\beta_{3}\tau^{3}n_{NF_{3},in}}{(1+\beta_{1}\tau)(1+\beta_{2}\tau)(1+\beta_{3}\tau)}$$
$$n_{F,F_{2}} = \frac{\beta_{F_{2}}\tau n_{F_{2},in}}{1+\beta_{F_{2}}\tau}$$
$$\beta_{i} \equiv k_{i}n_{e}$$

Uncertainty Analysis for NF₃ Etch Rate

Assume 10% uncertainty in A_i and E_{ai} , no uncertainty in β_i .

$$\begin{array}{ll} \mathsf{NF}_{3} + \mathsf{e} - \mathsf{r} > \mathsf{NF}_{2} + \mathsf{F} \cdot \mathsf{r} + \mathsf{e} \\ \mathsf{NF}_{2} + \mathsf{e} - \mathsf{r} > \mathsf{NF} + \mathsf{F} \cdot \mathsf{r} + \mathsf{e} \\ \mathsf{NF} + \mathsf{e} - \mathsf{r} > \mathsf{N} + \mathsf{F} \cdot \mathsf{r} + \mathsf{e} \\ \mathsf{F} \cdot \mathsf{r} + \mathsf{SiO2} - \mathsf{r} > \mathsf{SiF4} \\ \end{array} \begin{array}{l} k = A_{i} \cdot T_{e}^{\beta_{i}} \cdot e^{-E_{ai}/T_{e}} \\ k_{i} = A_{i} \cdot T_{e}^{\beta_{i}} \cdot e^{-E_{ai}/T_{e}} \\ \mathsf{r} = k \times n_{F} \times T_{s}^{1/2} \times \exp\left(-0.163 \times eV/k_{B}T_{s}\right) \end{array}$$



Parameters	Rank Correlation Coefficient
Intercept for $k_B^*T_e^{-E_e'/p}$	0.659466
Activation energy E_{a3} for NF ₃ decomposition	-0.65332
Rate constant <i>k</i> for etch reaction	0.227614
Activation energy E_{a2} for NF ₂ decomposition	-0.10335
Pre-exponential coefficient A ₃ for NF ₃ decomposition	0.093827

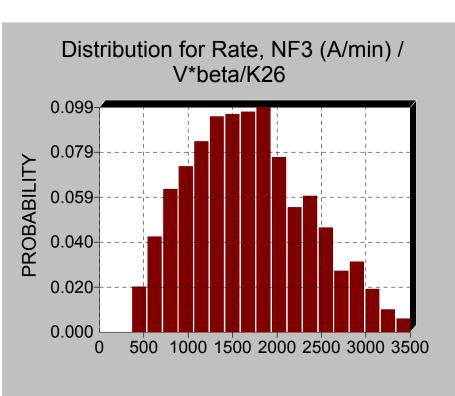
24



Parameters	Rank Correlation Coefficient
NF ₃ Yield in NF ₃ Production	-0.71
Energy Usage in F ₂ production	0.42
Intercept for $k_B * T_e \sim E = /p$	-0.39
Activation Energy E_{a3} for NF ₃ decomposition	0.34
Energy Usage in NH ₃ production	0.13

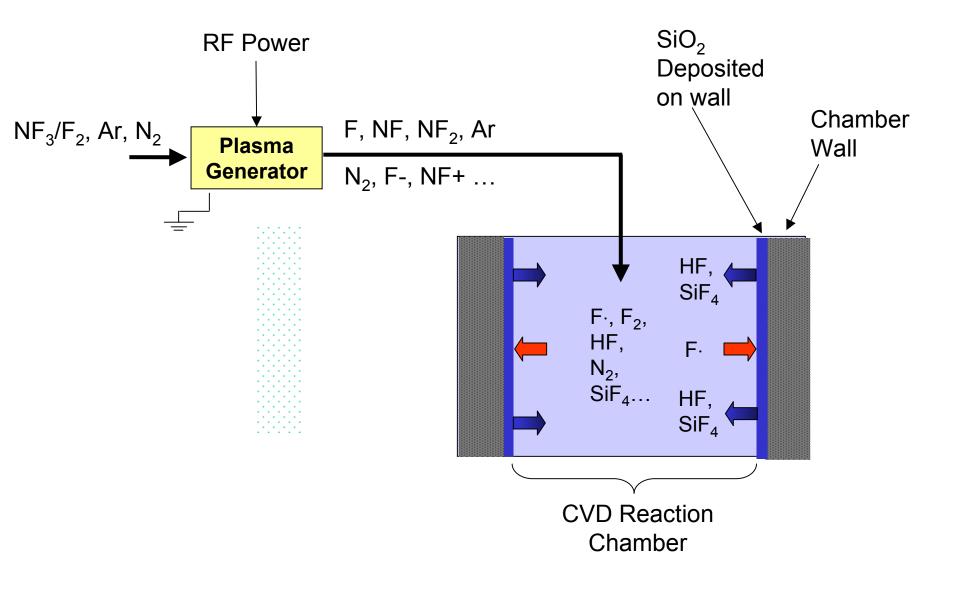


Assume 10% uncertainty in A_{i} , E_{ai} , and β_i .

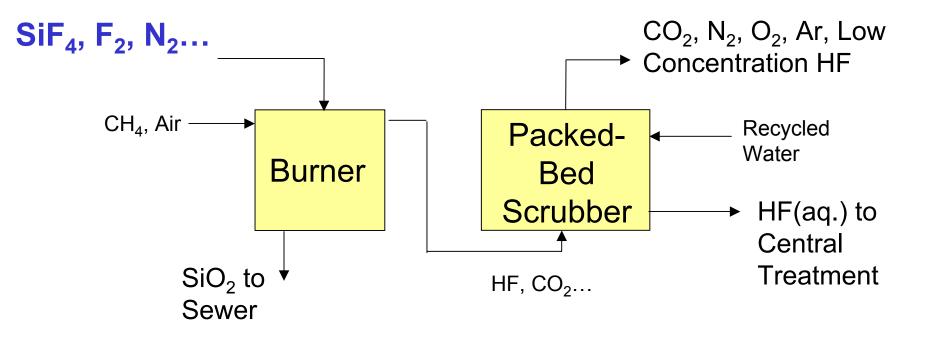


Parameters	Rank Correlation Coefficient
Power β_3 to the electron temperature for NF $_3$ decomposition	0.87
Activation Energy <i>E_{a3}</i> for NF3 decomposition	-0.27
Power β_2 to the electron temperature for NF2 decomposition	0.267
Intercept for $k_B^*T_e^{-E_e/p}$	0.24
Power β_1 to the electron temperature for NF decomposition	0.13

Chamber Cleaning with NF_3/F_2



Including Downstream Treatment



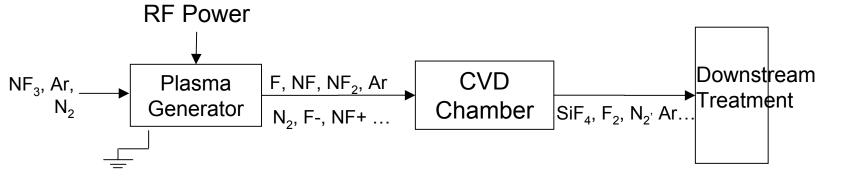
- Fuel Usage Similar
- Water Usage 548 gallon/yr for NF₃, 566 gallon/yr for F₂
 Insignificant compared to 1 million gallon/day

Case Study: NF₃ vs. F₂ as Chamber Cleaning Gas

- Merits of NF₃
 - High disassociation rate
 - High removal rate
 - High etch rate
- Drawback of NF₃
 - High cost
- NF₃ Cleaning Process in the Fab

- Merits of F₂
 - Low cost
- Drawbacks of F₂
 - High toxicity
 - High reactivity
 - POU generation creates explosive H₂

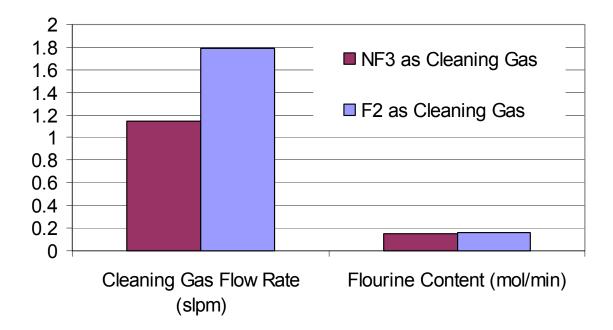
23



- Basis for Comparison Same etch Rate r_e for both processes
- Strategy Same process parameters except F_{cleaning gas, in}

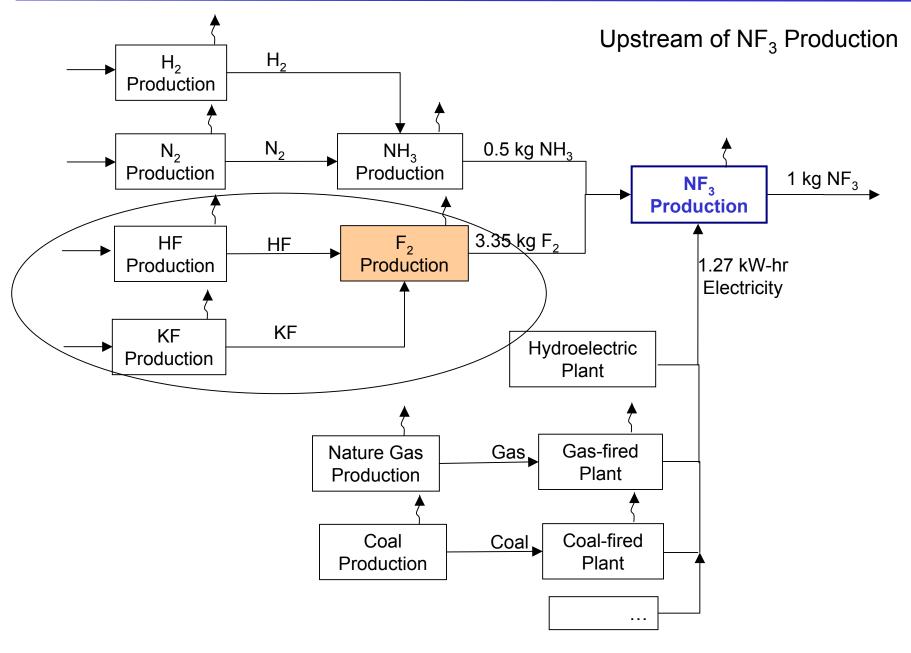
– Vary $F_{\text{cleaning gas, in}}$ to achieve same r_{e}

Comparison Boundary – Unit Process



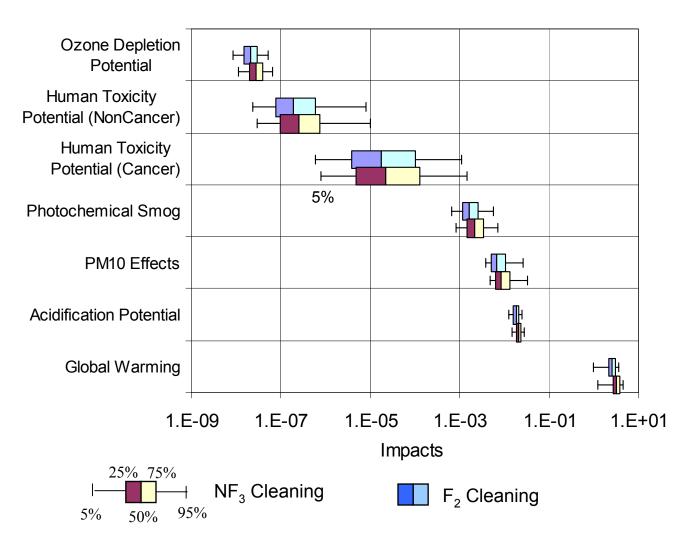
- Similar in Environmental Impacts due to the Same Power, Cleaning Time, and Chamber Temperature
- Similar in Cost of Running the Process

Including Upstream Processes



Comparison in the Life Cycle Boundary

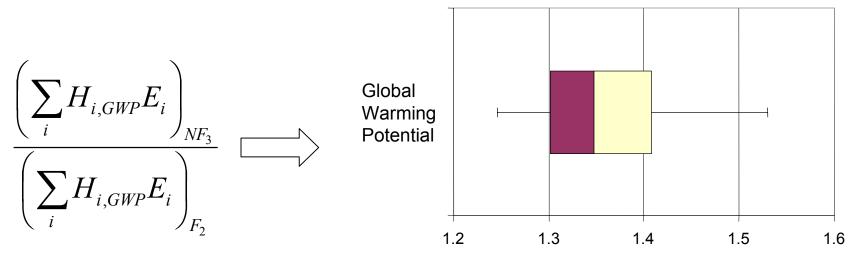
- NF₃ cleaning has higher impacts in all the areas than F₂
- Higher impacts due to energy generation for producing NF₃



- Ozone Depletion Potential (kg CFC-11 equivalent/kg)
- Human Toxicity Potential-NonCancer (DALYs/kg)
- Human Toxicity Potential-Cancer (DALYs/kg)
- Photochemical Smog (kg Ethylene equivalent/kg)
- PM10 Effects (kg PM10 equivalent/kg)
- Acidification Potential (kg SO2 equivalent/kg)
- Global Warming (kg CO2 equivalent/kg)

Relative Impact of Two Cleaning Processes

- Strong correlation between results of NF₃ case and F₂ case
- Reduce correlation effect by using relative values



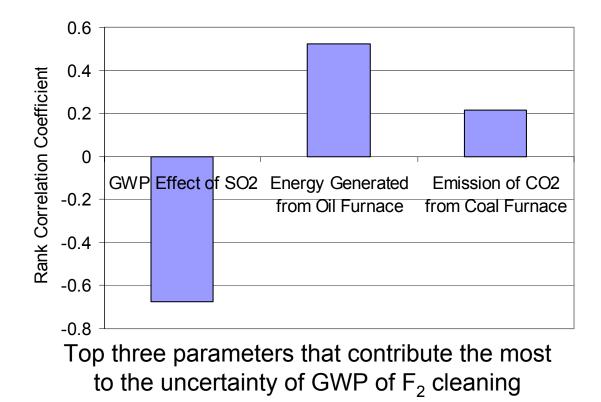
Relative Impact of NF3 Cleaning to F2 Cleaning

• Uncertainty of relative impact is much smaller than inputs

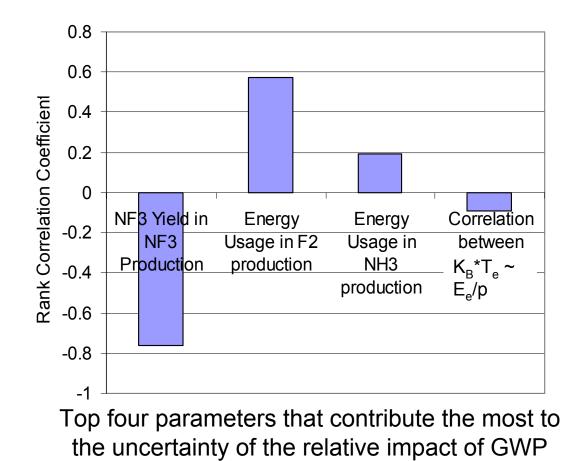


• Which parameters are important is also influenced by the goals of the analysis

34

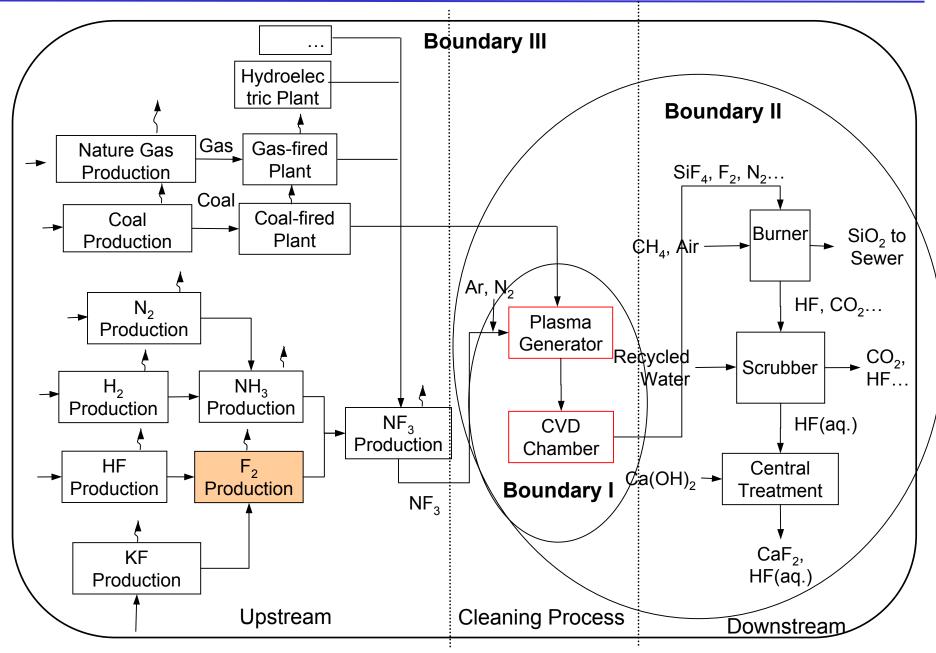


Identifying Important Parameters



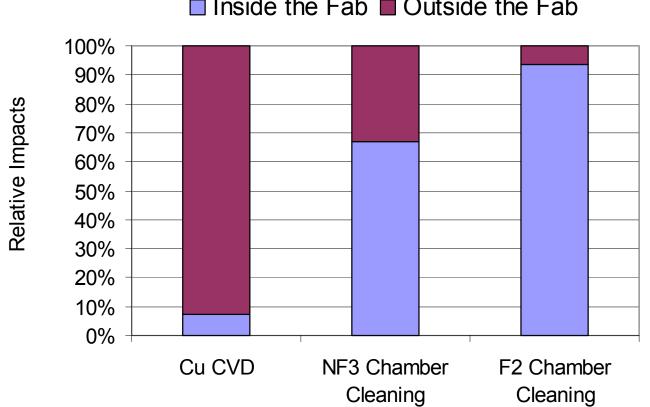
- Top three parameters are related to upstream production
- Identification of important parameters enables efficient allocation of data collection effort – spend money and time in the most valuable place!

Importance of Considering Multi-Boundaries



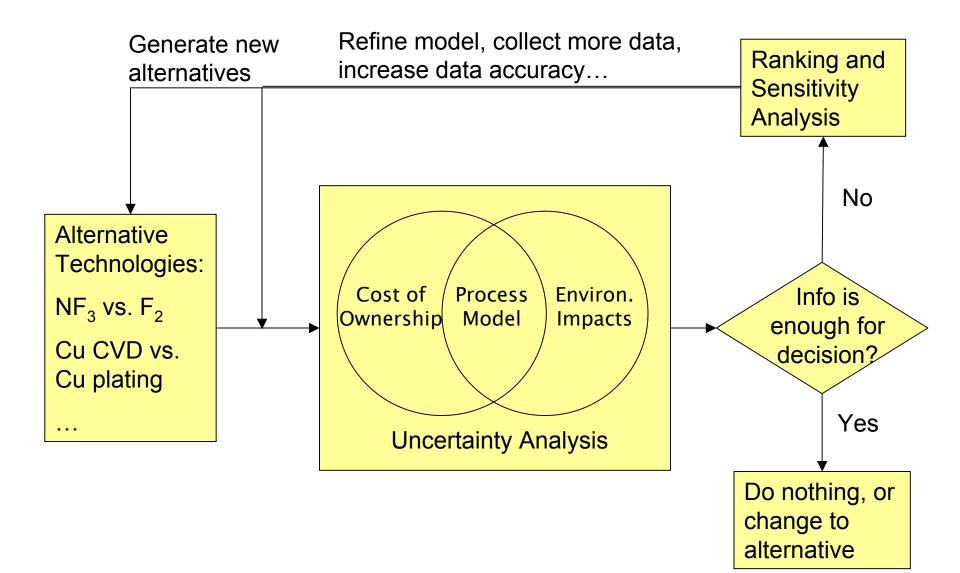
Boundary of Environmental Analysis

Boundary of the environmental analysis directly affects the results



Inside the Fab Outside the Fab

Framework of Decision-Making Process



30

- The integration of process models, COO, and environmental evaluations is critical and doable.
- Large uncertainty in the inputs does not necessarily lead to low confidence in decisions.
- System boundaries strongly affect the outcomes of the evaluations.



- Laura Losey, David Bouldin, Mike Kasner, Tim Yeakley, Larry Novak, Daren Dance, Tina Gilliland – Texas Instruments
- Alejandro Cano-Ruiz and Pauline Ho Reaction
 Design
- Joe Van Gompel **BOC Edwards**
- Karen Gleason, Herb Sawin and Joel Clark MIT
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End of Presentation

4